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THE UNITED STATES PATENT AND TRADEMARK OFFICE

Appl. No. : 10/802,728
Applicant : Oliver Broermann et al.
Filed : March 18, 2004
TC/A.U. : 2877
Examiner : Pham, Hoa Q.
Confirmation No. : 5025
Docket No. : 3000.0043C
Customer No. : 054500
Title : Method for Measuring a Characteristic Dimension
of at Least One Pattern on a Disc-Shaped Object in
a Measuring Instrument

Certificate
JAN 17 2006
of Correction

ATTN: Certificate of Correction Branch

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

TRANSMITTAL LETTER

Sir:

Transmitted herewith are a Request for Certificate of Correction Under 37 C.F.R. §1.322 (1 page); and a Certificate of Correction Form PTO/SB/44 (2 pages). Due to an error by the U.S. Patent and Trademark office, claims 4-14 in the issued patent are erroneous.

The Commissioner is hereby authorized to charge payment of any additional fees required for the above-identified application or credit any overpayment to Deposit Account No. 05-0460.

Respectfully submitted,

Patrick J. Finnan
Registration No. 39,189

Hand-delivered: 1/12/06

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Request for Certificate of Correction Under 37 C.F.R. §1.322

Sir:

A Certificate of Correction is respectfully requested to correct claims 4-14, which are incorrect in the issued patent due to an error by the U.S. Patent and Trademark Office.

A completed Form PTO/SB/44 is attached herewith showing the correction to be made.

The Commissioner is hereby authorized to charge payment of any additional fees required or credit any overpayment to Deposit Account No. 05-0460.

Respectfully submitted,

Patrick J. Finnan
Registration No. 39,189

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JAN 18 2006

UNITED STATES PATENT AND TRADEMARK OFFICE CERTIFICATE OF CORRECTION

PATENT NO. : 6,980,304 B2

DATED : Dec. 27, 2005

INVENTOR(S) : Oliver Broermann, et al.

Page 1 of 2

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

Claims 4-14 should read:

4. The method according to claim 1, wherein in the case of a plurality of parameters, the computing and control unit calculates one quality parameter the quality parameter representing the quality of the measurement from the calculated parameters, the quality parameter being compared with a prescribed quality limiting value, a warning signal being generated as a function of the comparison.

5. The method according to claim 3, wherein for the measuring step of the alignment, the measured data obtained in this measuring step includes a digital image, the computing rule for calculating the value of the relevant parameter includes the comparison of the digital image with a reference image.

6. The method according to claim 3, wherein for the measuring step of the detection of the at least one pattern, the measured data obtained includes a digital image, the computing rule for calculating the value of the relevant parameter includes the comparison of the digital image with a reference image.

7. The method according to claim 3, wherein for the measuring step of aligning the lens system, the measured data obtained includes a measuring curve, the computing rule for calculating the value of the parameter relating to the measuring step includes the comparison of the measuring curve with a reference curve.

8. The method according to claim 3, wherein the measuring step of the characteristic dimension is carried out with the aid of at least two measurements of the at least one pattern, the computing rule of the parameter relating to the pattern width measuring step includes the comparison of a first measuring curve of a first measurement with a second measuring curve of a second measurement.

MAILING ADDRESS OF SENDER:

Edell, Shapiro & Finnan, LLC
1901 Research Blvd., Suite 400
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PATENT NO. 6,980,304 B2

No. of additional copies



This collection of information is required by 37 CFR 1.322, 1.323, and 1.324. The information is required to obtain or retain a benefit by the public which is to file (and by the USPTO to process) an application. Confidentiality is governed by 35 U.S.C. 122 and 37 CFR 1.14. This collection is estimated to take 1.0 hour to complete, including gathering, preparing, and submitting the completed application form to the USPTO. Time will vary depending upon the individual case. Any comments on the amount of time you require to complete this form and/or suggestions for reducing this burden, should be sent to the Chief Information Officer, U.S. Patent and Trademark Office, U.S. Department of Commerce, P.O. Box 1450, Alexandria, VA 22313-1450. DO NOT SEND FEES OR COMPLETED FORMS TO THIS ADDRESS. SEND TO: Attention Certificate of Corrections Branch, Commissioner for Patents, P.O. Box 1450, Alexandria, VA 22313-1450.

If you need assistance in completing the form, call 1-800-PTO-9199 and select option 2.

JAN 18 2006

UNITED STATES PATENT AND TRADEMARK OFFICE CERTIFICATE OF CORRECTION

PATENT NO. : 6,980,304 B2
DATED : Dec. 27, 2005
INVENTOR(S) : Oliver Broermann, et al. Page 2 of 2

It is certified that error appears in the above-identified patent and that said Letters Patent is hereby corrected as shown below:

9. The method according to claim 1, wherein the disc-shaped object is a semiconductor wafer, a mask, or a reticule or a flat panel display.

10. The method according to claim 1, wherein the measuring step is repeated for a multiplicity of disc-shaped objects, the value of the parameter for the respective measuring step is stored in a database, and a trend analysis is carried out for the parameter over the multiplicity of the respectively stored values.

11. The method according to claim 4, wherein for the measuring step of the alignment, the measured data obtained in this measuring step includes a digital image, the computing rule for calculating the value of the relevant parameter includes the comparison of the digital image with a reference image.

12. The method according to claim 4, wherein for the measuring step of the detection of the at least one pattern, the measured data obtained includes a digital image, the computing rule for calculating the value of the relevant parameter includes the comparison of the digital image with a reference image.

13. The method according to claim 4, wherein for the measuring step of aligning the lens system, the measured data obtained includes a measuring curve, the computing rule for calculating the value of the parameter relating to the measuring step includes the comparison of the measuring curve with a reference curve.

14. The method according to claim 4, wherein the measuring step of the characteristic dimension is carried out with the aid of at least two measurements of the at least one pattern, the computing rule of the parameter relating to the pattern width measuring step includes the comparison of a first measuring curve of a first measurement with a second measuring curve of a second measurement.

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